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OverView

Specifications



OverView

- IIM-3000 is a equipment that detects all defects and measures the size of each defect on 300 mm Si wafers. Followings are the types of defects that IIM-3000 can detect ; Buried airpockets, Bumps and Through-holes.
- The advanced defect detection and classification algorithms, enable users to detect easily all defects in various Si wafers(N. P-, P +, P ++) with high throughput.
- A specialized controller for IIM-3000 provides the optimized control unit, which enables easy maintenance and quick setup.
- By applying optimized software, IIM-3000 provides reliable inspection quality and result data for users also.

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